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<b>SERIAL NUMBER</b> 10/527,642	<b>FILING OR 371(c) DATE</b> 03/14/2005 <b>RULE</b>	<b>CLASS</b> 438	<b>GROUP ART UNIT</b> 2812	<b>ATTORNEY DOCKET NO.</b> 267410US26PCT
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**\*\* CONTINUING DATA \*\*\*\*\***

This application is a 371 of PCT/JP03/11971 09/19/2003 *CL*

**\*\* FOREIGN APPLICATIONS \*\*\*\*\***

JAPAN 2002=273709 09/19/2002 *CL*

Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no	<b>STATE OR COUNTRY</b> JAPAN	<b>SHEETS DRAWING</b> 15	<b>TOTAL CLAIMS</b> 20	<b>INDEPENDENT CLAIMS</b> 5
35 USC 119 (a-d) conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after				
Verified and Acknowledged	Examiner's Signature <i>Chung</i>	Initials <i>CL</i>		

**ADDRESS**

22850

**TITLE**

Method for forming insulating film on substrate, method for manufacturing semiconductor device and substrate-processing apparatus

<b>FILING FEE RECEIVED</b> 1710	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees
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